



Att. Docket No. 10191/1690

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. Serial No. : 09/762,985 Confirmation No. 2674

Title : DEVICE AND METHOD FOR
ETCHING A SUBSTRATE USING
AN INDUCTIVELY COUPLED PLASMA

Applicant(s) : Volker BECKER et al.

Filed : May 8, 2001

TC/A.U. : 1763

Examiner : Luz L Alejandro Mulero

Docket No. : 10191/1690

Customer No. :

26646 I hereby certify that this correspondence is being deposited with the

United States Postal Service with sufficient postage as first class mail

in an envelope addressed to:

Mail Stop AMENDMENT, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

on

Date: 8/19/2005

Signature: Aaron C. Beditch

AMENDMENT (33,865)

SIR:

In response to the Office Action mailed on February 23, 2005 (the three-month response date for which has been extended by three months from May 23, 2005 to August 23, 2005 by the accompanying Transmittal and Petition to Extend), please reconsider the above-identified application based on the following:

Amendments to the Claims are reflected in the listing of the claims which begins on page 2 of this paper.

Remarks begin on page 8 of this paper.